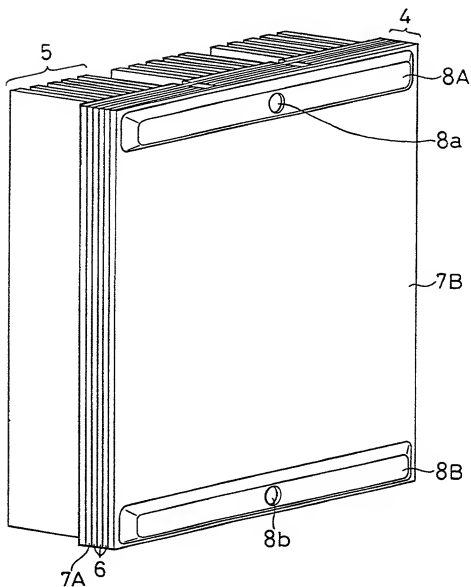
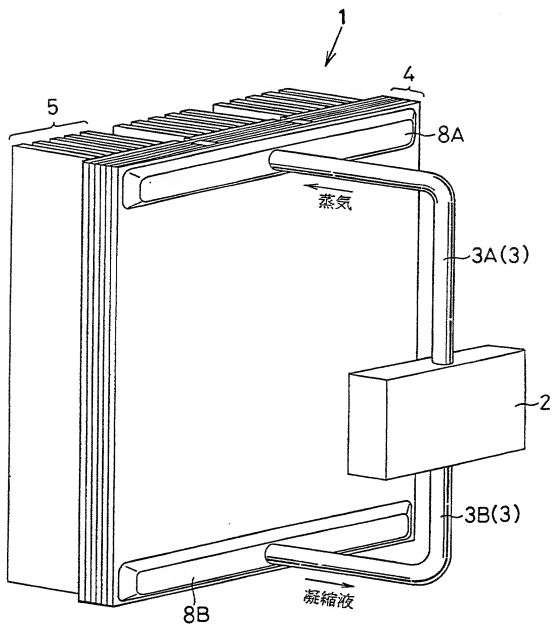


図2



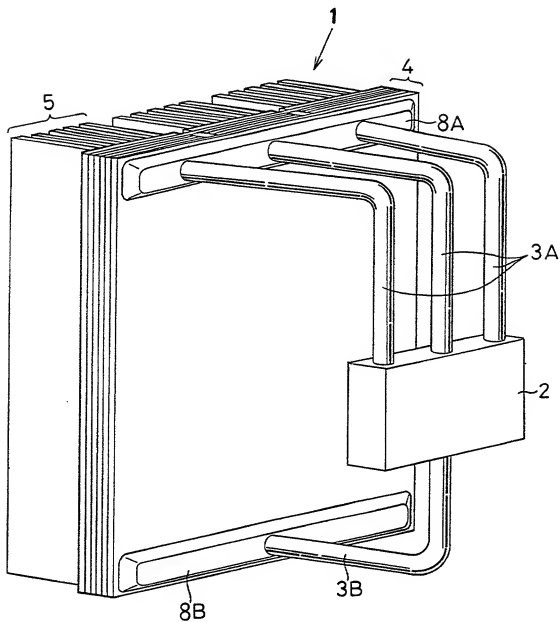
10047914-01502

図3



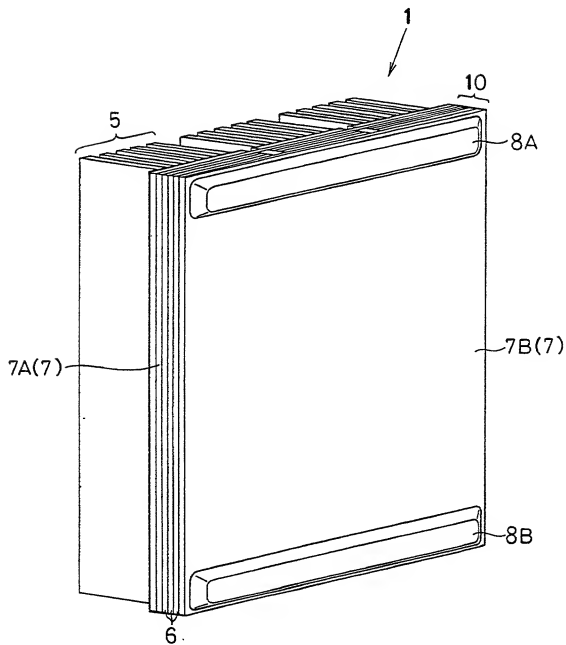
10047914.013502

図 4



10047914-011502

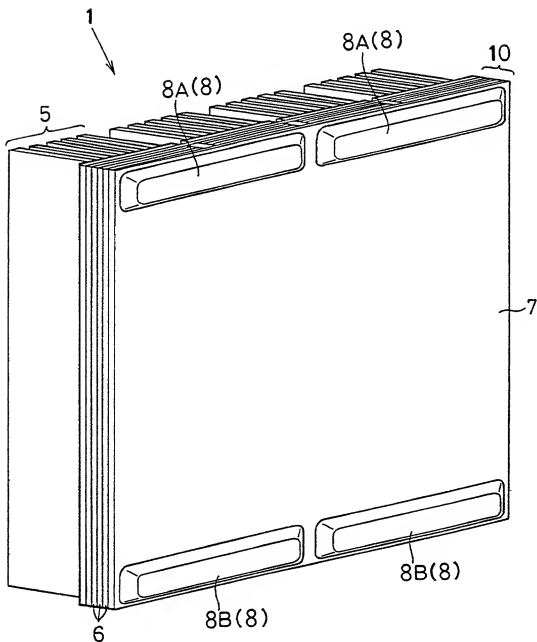
図5



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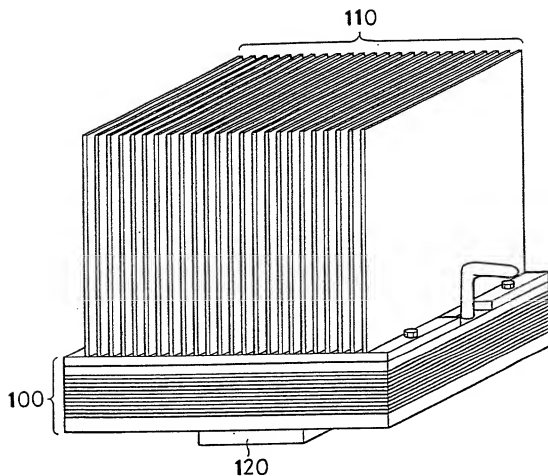
図6



10047914.011502

図7

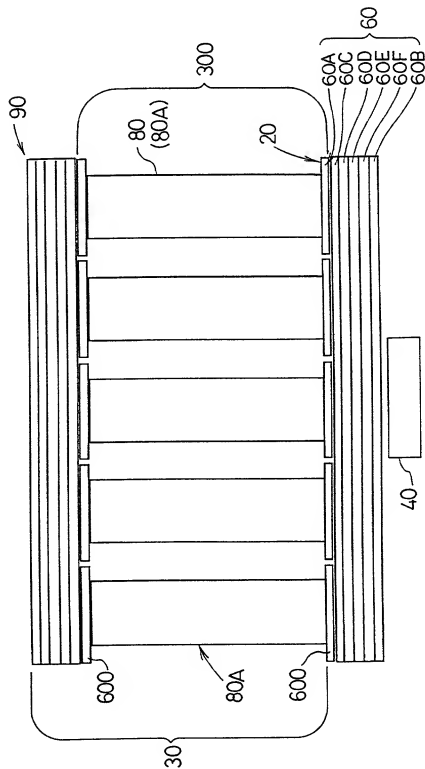
従来技術



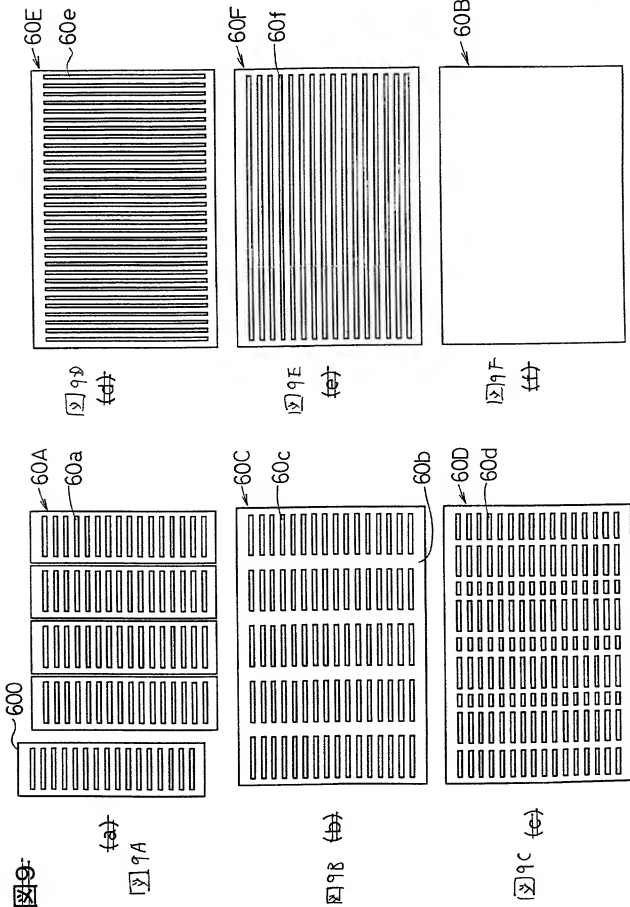
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図10

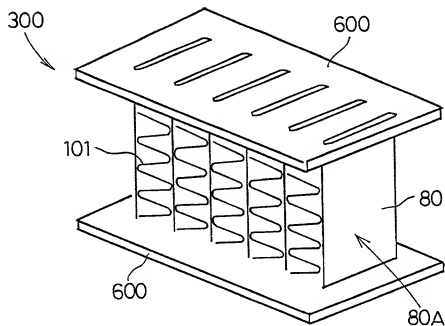


図11

図 11A

(a)

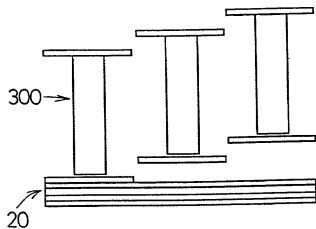
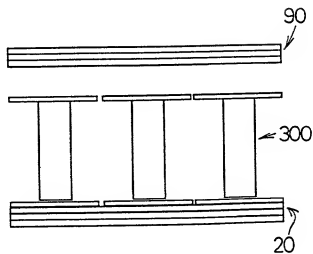


図 11B

(b)



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図12

図12A

(a)

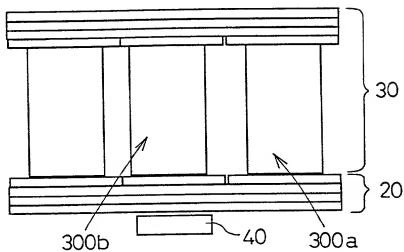


図12B

(b)

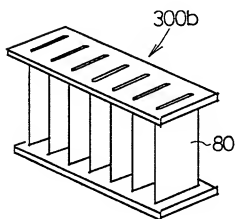
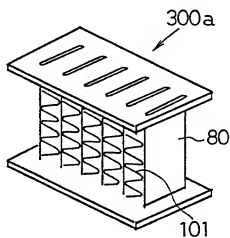


図12C

(c)

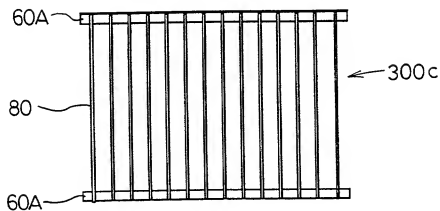


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FIG 13

13A
(a)



13B
(b)

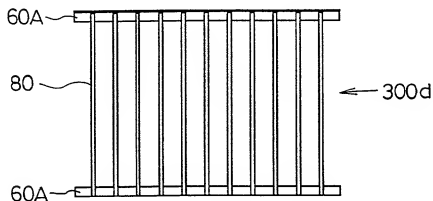
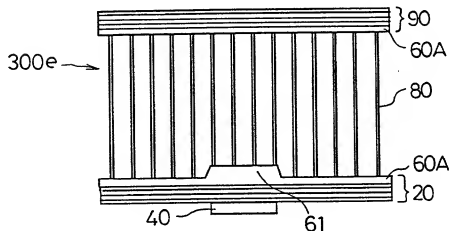


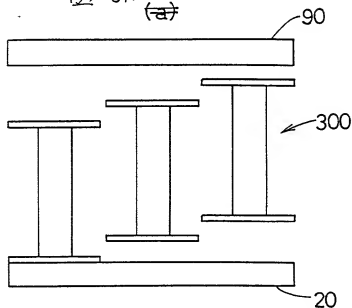
FIG 14



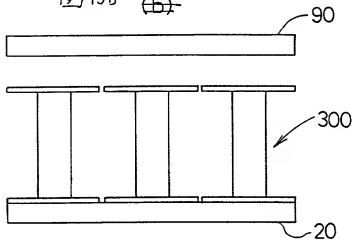
10047914.011502

図15

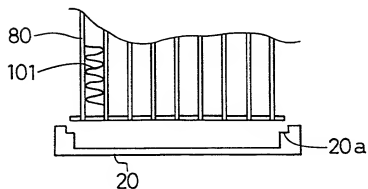
15A (a)



15B (b)



15C (c)



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FIG 16

FIG 16A

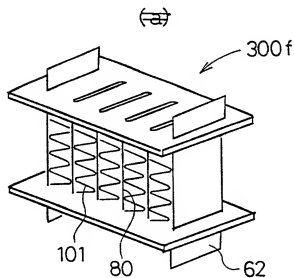
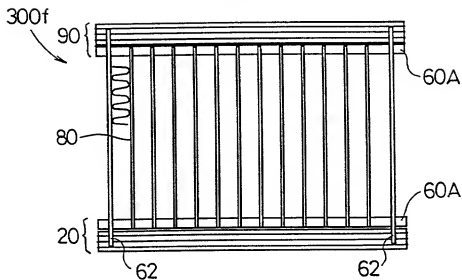


FIG 16B

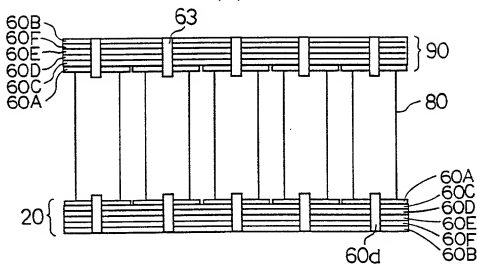
(b)



17A

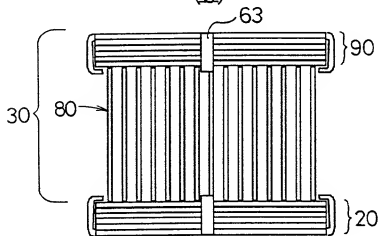
17

(a)



17B

(b)



18

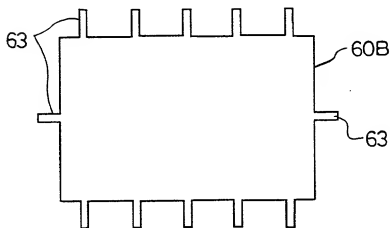


図19

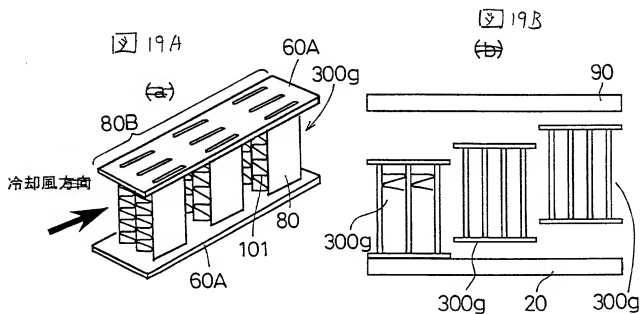


図20

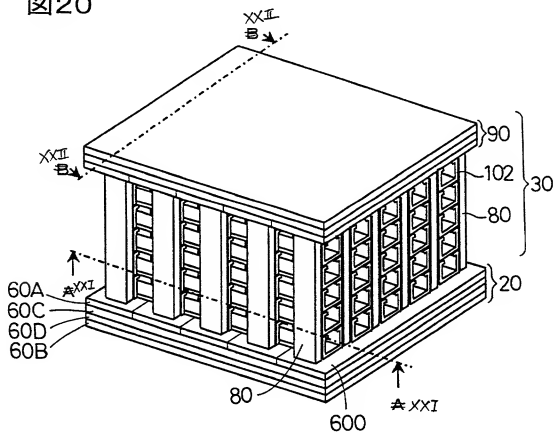


図21

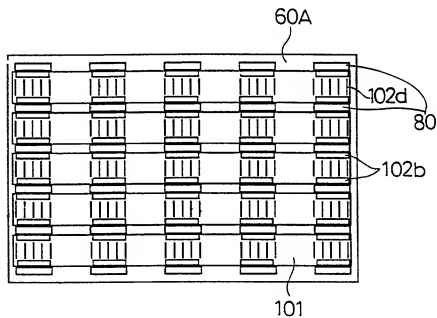
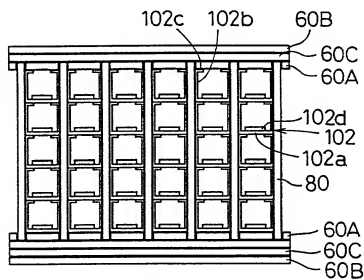


図22



10047914.011502

図23

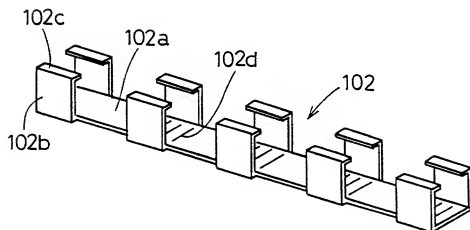
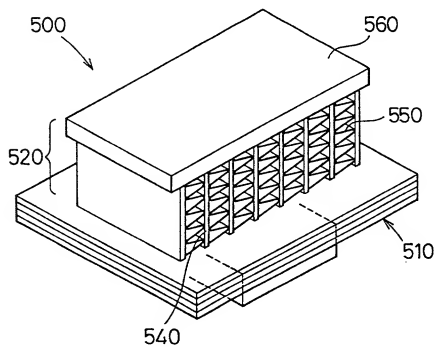


図26

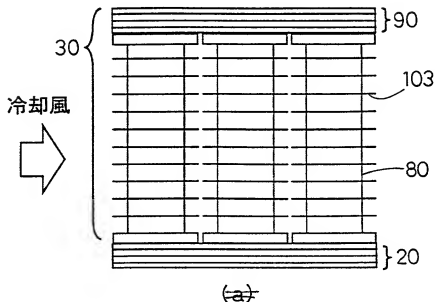
従来技術



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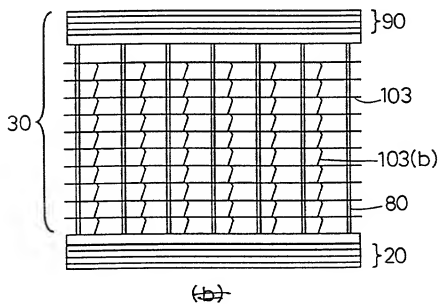
図24

図24A



(a)

図24B



(b)

図25

